

Electronic Patent Application Fee Transmittal

Application Number:	10573406			
Filing Date:	27-Mar-2006			
Title of Invention:	SPUTTERING TARGET AND PROCESS FOR PRODUCING SI OXIDE FILM THEREWITH			
First Named Inventor/Applicant Name:	Koichi Watanabe			
Filer:	Pavan K. Agarwal/Renell Feimster			
Attorney Docket Number:	017447-0194			
Filed as Large Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Utility Appl issue fee	1501	1	1510	1510
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Total in USD (\$)				1810